

ABSTRACT

1 A semiconductor workpiece processing system comprising at  
2 least one processing tool, a container, a first transport  
3 section, and a second transport section. The processing  
4 tool is used for processing semiconductor workpieces.  
5 The container is used for holding at least one  
6 semiconductor workpiece therein for transporting two and  
7 from the processing tool. The first transport section is  
8 connected to the processing tool for transporting the  
9 container to and from the processing tool. The second  
10 transport section is connected to the first transport  
11 section for transporting the container to and from the  
12 processing tool. The first transport section is vehicle  
13 based having a transport vehicle capable of holding the  
14 container and moving along a first track of the first  
15 transport section. The second transport section is not  
16 vehicle based and has a second track with at least one  
17 support element thereon adapted to interface with the  
18 container for movably supporting the container from the  
19 second track and allowing the container to move relative  
20 to the first track. The first track and second track are  
21 disposed proximate to each other to allow the container  
22 to moved therebetween in one move.